

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Koichiro KISHIMA et al.

International Application No.: PCT/JP2004/016188

International Filing Date: October 25, 2004

For: METHOD FOR MANUFACTURING
SEMICONDUCTOR SUBSTRATE AND
SEMICONDUCTOR SUBSTRATE

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Sir:

Pursuant to 35 U.S.C. 119, this application is entitled to a claim of priority to U.S. Provisional Application No. 60/514,379 filed on October 24, 2003.

Respectfully submitted,

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